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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: ONO et al

Serial No.: 10/754,594

Filed: January 12, 2004

For: A Specimen Surface Processing Method And Apparatus

Art Unit: 1765

Examiner: K. Chen

**AMENDMENT**

Mail Stop: Amendment (Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

December 12, 2005

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated September 12, 2005. The amendments are listed below and set forth on the following pages.

Amendments to the Specification; and

Remarks are included following the amendments.